



[WD2] Modeling and Simulation of CCP and ICP	
Date / Time	July 25 (Wed.), 2018 / 13:20-14:50
Place	Room D (#115)
Session Chair(s)	Kosuke Yamamoto (Tokyo Electron Tech., Japan) Julian Schulze (Ruhr Univ. of Bochum, Germany)

WD2-1 [Invited]

13:20-13:50

Fluid and PIC Simulations on Electronegative SiH₄ and O₂ Discharges in RF CCPs

Wen-Zhu Jia, Li Wang, Yuan-Hong Song, and You-Nian Wang

Dalian Univ. of Tech., China

WD2-2

13:50-14:10

GEC-CCP Modelling Using Two-Dimensional Fluid Simulation Base on Stabilized Finite Element Method

Hyonu Chang

NFRI, Korea

WD2-3

14:10-14:30

Deduction of a Novel Electron Energy Equation in Fluid Model and Its Applications in Predicting the Electron Temperature Behavior of Inductive Coupled Plasmas

Shu-Xia Zhao

Dalian Univ. of Tech., China

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14:30-14:50

Energy Relaxation Kinetics for the Control of Electron Energy Distributions and Electron Heating Modes in a Capacitively Coupled RF Plasma

Jung Yeol Lee, Chang Ho Kim, and Jung Yeol Lee

Pusan Nat'l Univ., Korea